

# **20-nm (Planar) Mixed-Signal IP A Stepping Stone To FinFET?**

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April 2013



- Is this true?
- Is this the right question from a mixed-signal designer's perspective?

# ***Recent Industry Comments Supporting The “Stepping Stone”***

*“To accelerate FinFET efforts foundries are looking at hybrid integration schemes and “modular fin” strategies”*

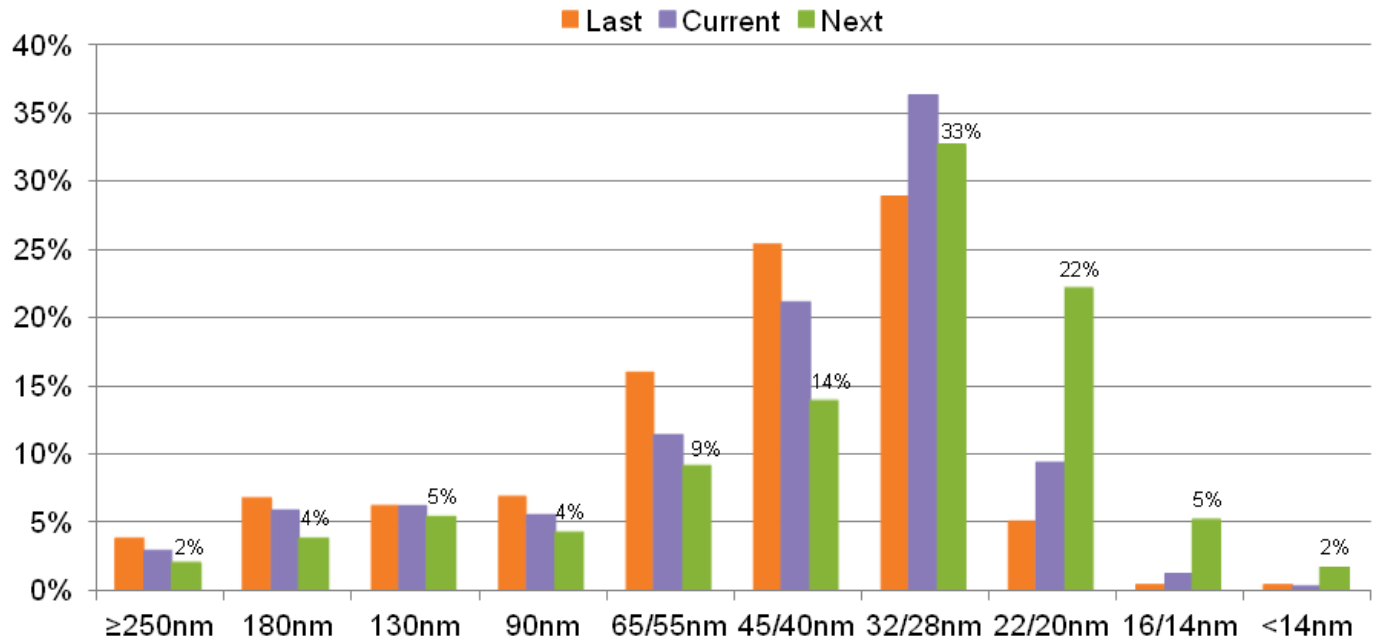
*“By being modular, vendors have the option to plug in the FinFET into an existing 20-nm planar BEOL flow.”*

# Power, Performance, Area (PPA) Driving Node Migration

What is the process technology of your design (closest drawn line width)?

GLOBAL 2012

Power Performance Requirements Drive Node Migrations



Planar → FinFET

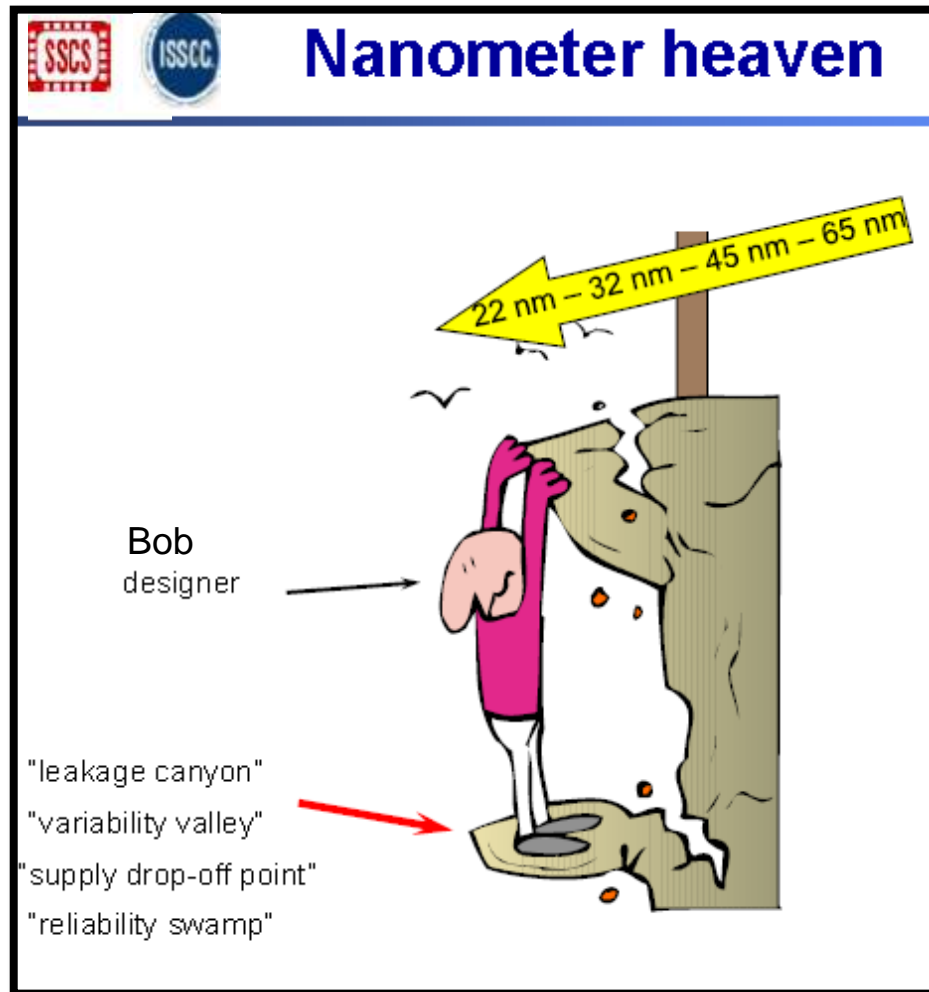
What is the process technology of your design (closest drawn line width)?

2012 Last N = 1,648

2012 Current N = 1,623

2012 Next N = 1,440

# Bob's Challenge



- 65-nm to 20-nm planar has involved design challenges to meet PPA in an SoC
- Can the planar architectures, know-how be applied to FinFET designs?

Is it a stepping stone?

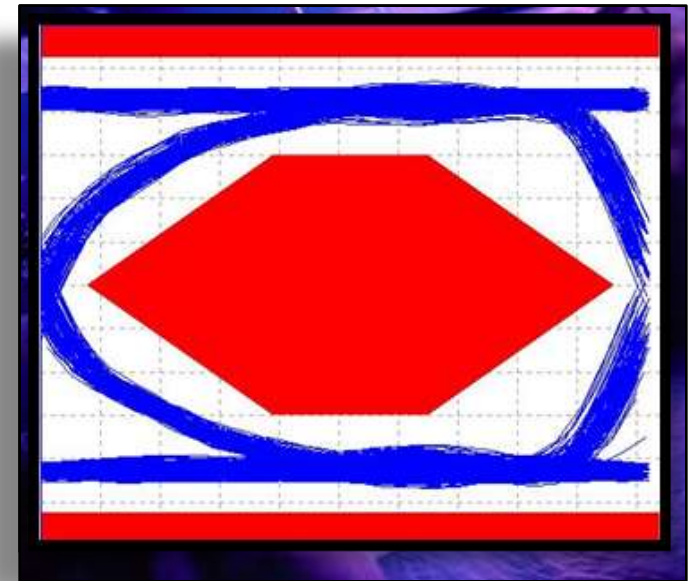
# Agenda

20-nm Design Requirements

Advanced Design Methodology

Stepping Stone To FinFET

Summary



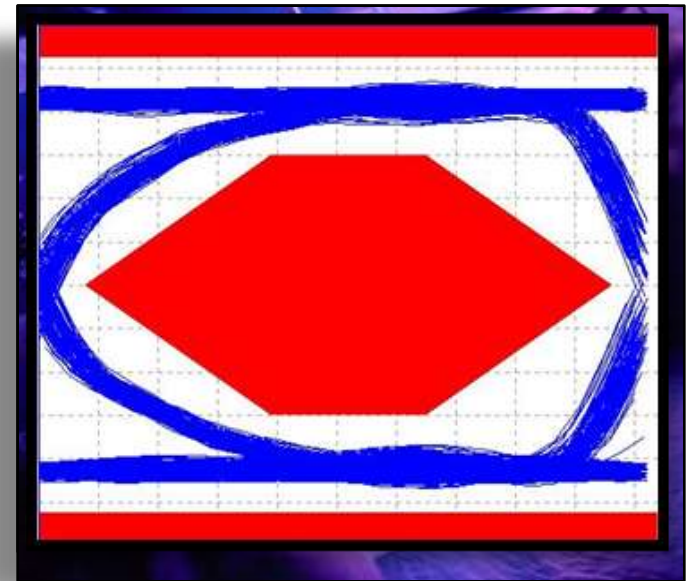
# Agenda

## 20-nm Design Requirements

Advanced Design Methodology

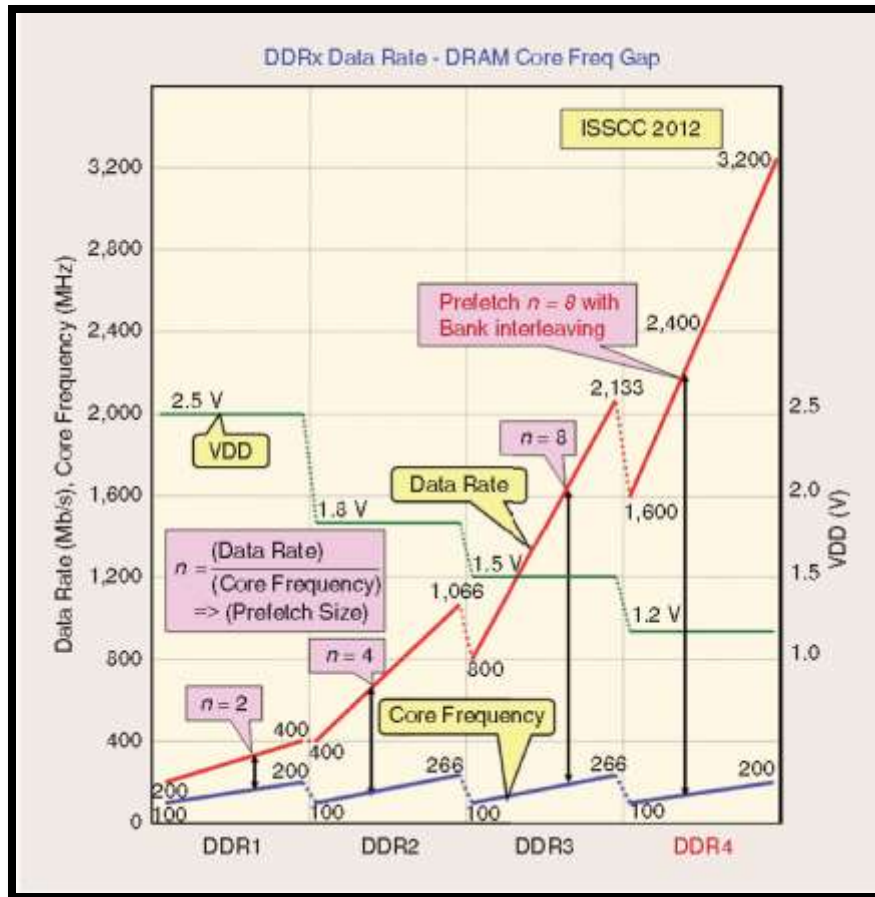
Stepping Stone To FinFET

Summary



# LPDDR3 – Drives Foundry I/O Strategy

## DDR4 – Drives Speed



### Specifications

- Evolving serial/parallel termination schemes
  - DDR4 is series + parallel to VDDQ
  - LPDDR3 tries to avoid termination
- Single ended interface
- DDR4: 1.2V 3.2 Gb/s
- LPDDR3: 1.2V 1600 Mb/s
- Need larger pre-fetch size, bank interleaving

### 20-nm design challenges

→ Better density, but  $V_t$  not scaling

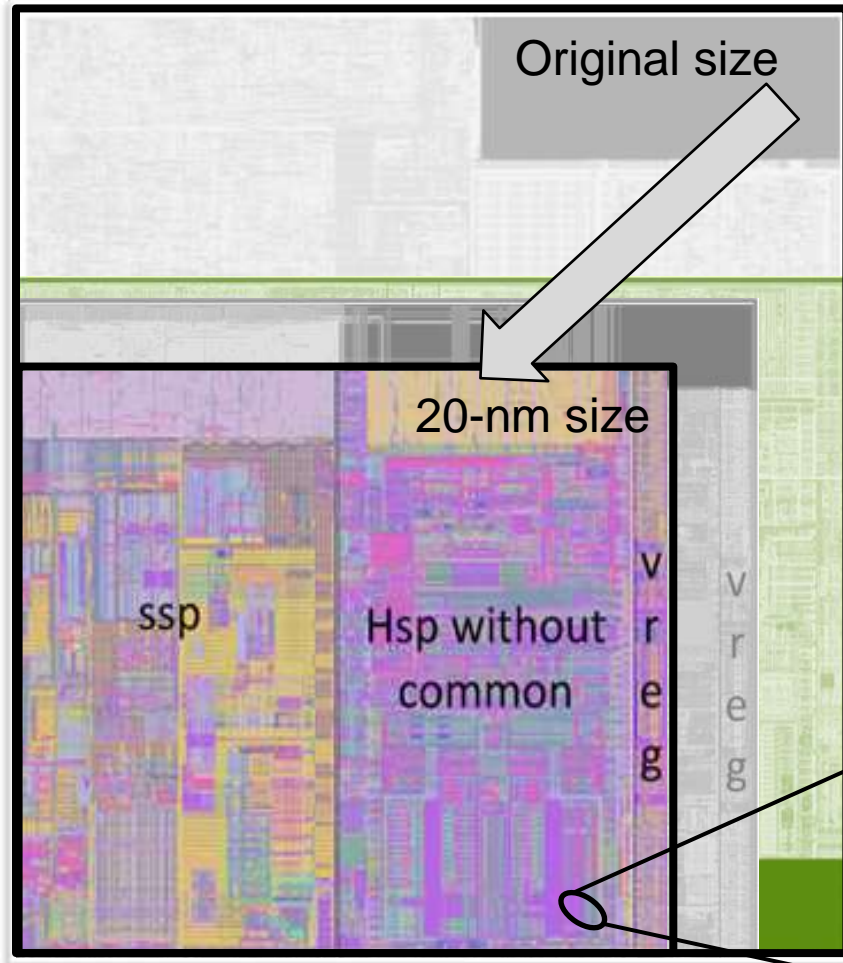
PPA target: DDR4 speed; LPDDR3 speed/low power



# USB 3.0, 20-nm 1.8V I/O

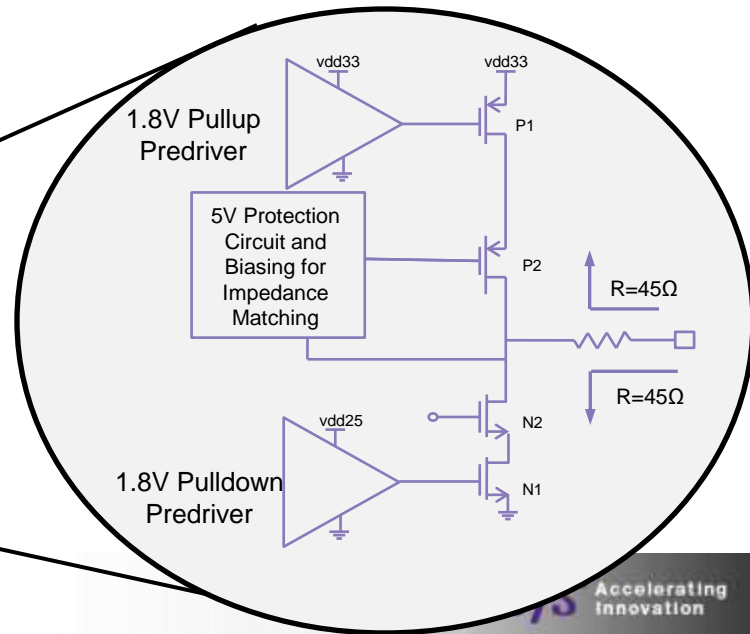
*Smaller area and electrical compliance must be met*

- **Must support all four USB speeds:**  
5 Gb/s, 480 Mb/s, 12 Mb/s, 1.5 Mb/s
- **5 V USB electrical compliance requirement**
  - Must be met using devices 1.8 V devices
  - Guaranteed device reliability meeting 3.3 V signal swings during Full Speed & Low Speed USB operation
  - Successfully operates after shorting the differential signal pair to 5 V for 24 hours
- **NBTI (high voltage overstress)** will impact receiver squelch threshold → causing electrical compliance failure



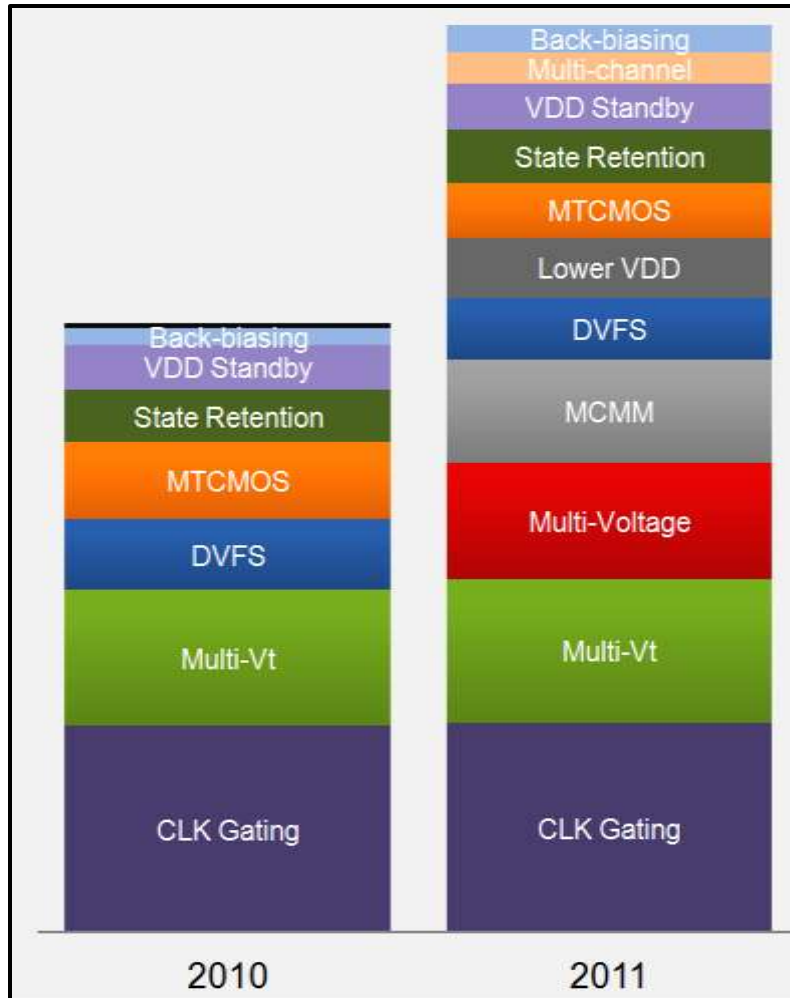
## PPA target

Area reduction; 5V battery charging; all 4 USB speeds

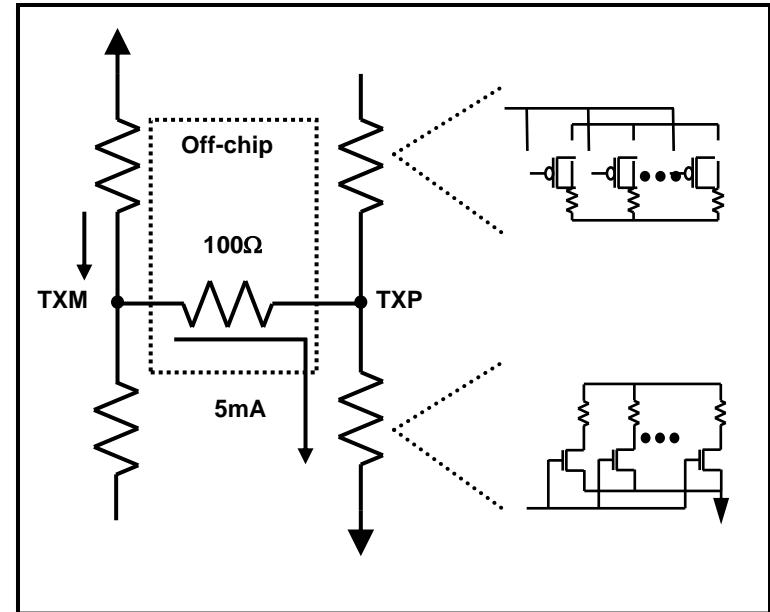


# PCI Express: Lowering Power

*Design techniques plus new specs*



PPA target: speed, new low power modes



Low-power design techniques

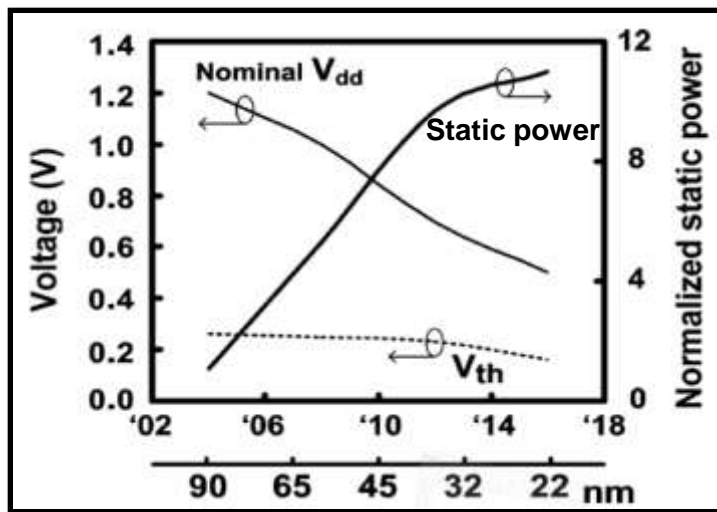
Low-power architectures

New PCI Express specifications

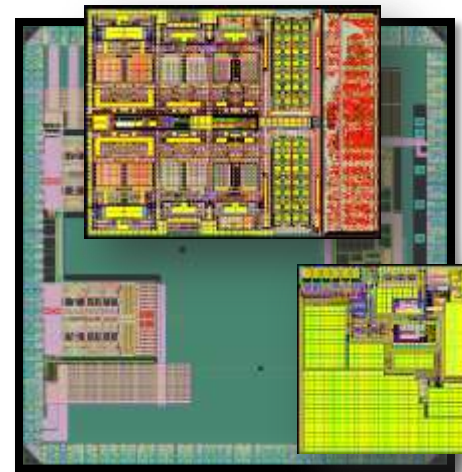
# Data Converters

## *Meeting dynamic range*

- Supply voltage almost halved from 65-nm to 20-nm
- Analog video / audio dynamic range > 1.3V means no voltage headroom for high linearity @ 1.8V supply
- Flicker (1/f) noise inversely proportional to transistor length (L)
- New analog techniques: clock boosting circumvents low supply voltage, internally processing signals with large voltage swings



Source: ITRS roadmap, supply voltage and threshold voltage



Synopsys : LTE analog front-end using 1.8 V

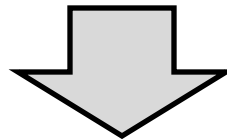
# 20-nm PPA Requirements

## IP Specifications:

- DDR4, LPDDR4 → higher I/O speeds using single-ended interface
- USB 3.0 → must support all 4 speeds, meet electrical compliance
- PCI Express → 5 Gb/s, 8 Gb/s but support new low power modes
- Data converters → dynamic range versus lower voltage headroom

## Market requirement:

- Physical IP scales (area, power) without performance degradation
- Supports aggressive schedules → designed on an early PDK
- Works on first instantiation in SoC



**Requirements: advanced silicon design methodology and close co-operation with foundry**

# 20-nm Layout Dependent Effects

Semiconductor Process Requirements

- WPE
- LOD
- OSE
- PSE
- PO.DN.15
- Pattern Density Effect
- OPC (Optical Proximity Check)
- GDA (Gross Die Advisor) Criteria
- MFU (Mask Field Utilization) > 80%
- DFM LPC (Layout Patterning Check)
- HCI (Hot Carrier effect Injection)
- Dummy OD (DOD) rules
- Dummy Poly (DPO) rules
- SM (Stress Migration)
- NBTI
- PBTI
- PSM
- RTO

PPA  
Requirements  
For Physical IP

Technology  
Assessment  
Chip



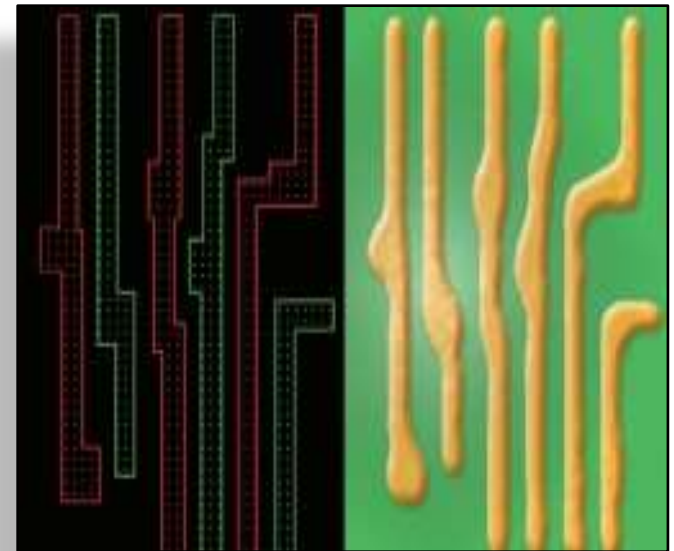
# Agenda

20-nm Design Requirements

**Advanced Design Methodology**

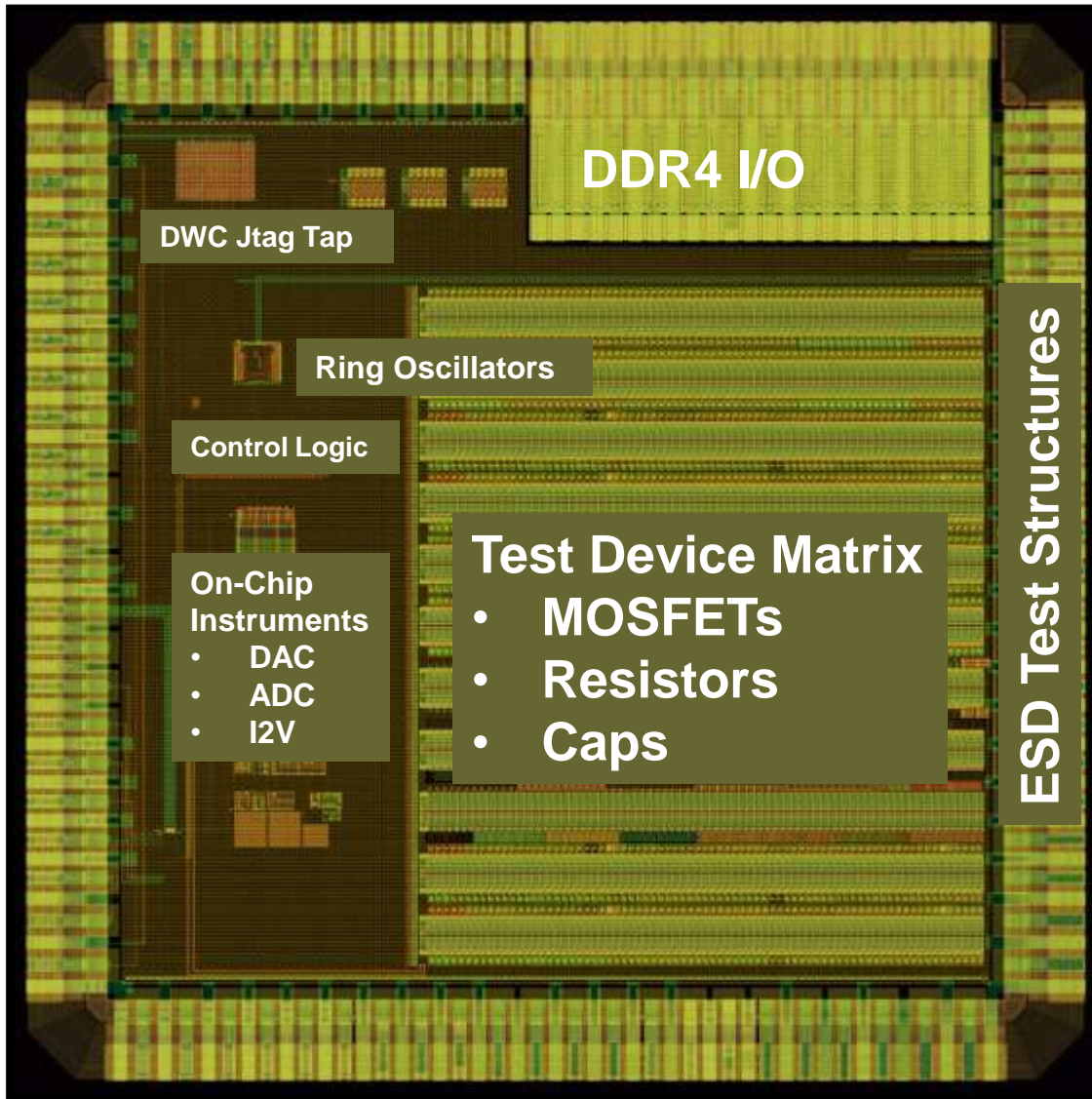
Stepping Stone To FinFET

Summary



# Enabling Robust IP Development

## *Analog Technology Assessment Chip*

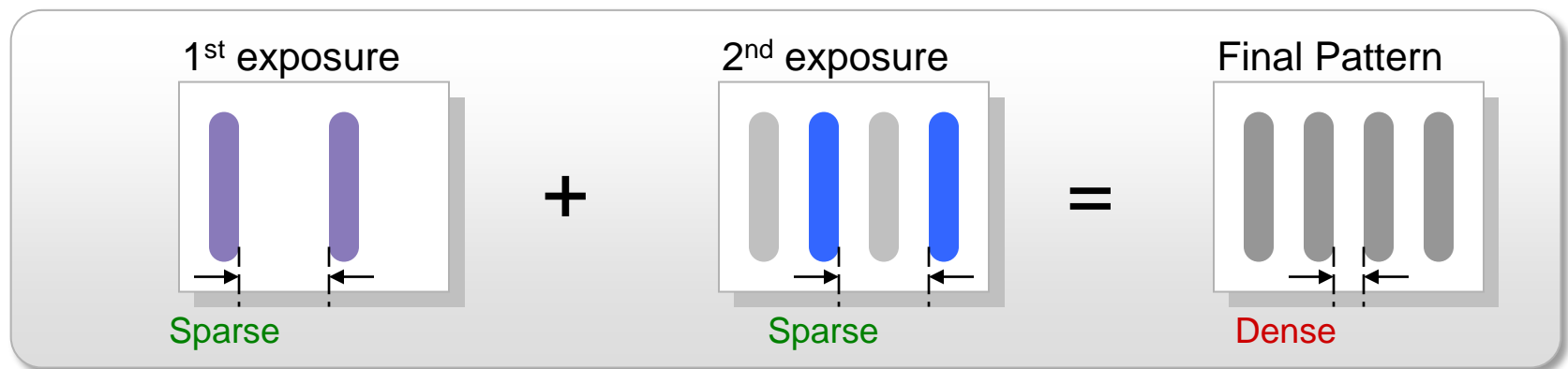


- CAD flow verification
- Correlate to simulation
- Fundamental IP structures:
  - Ring oscillators
  - DDR4 I/O
  - Analog IP
  - Test devices

# Technology Assessment Chip

## *Focused on analog/mixed-signal requirements*

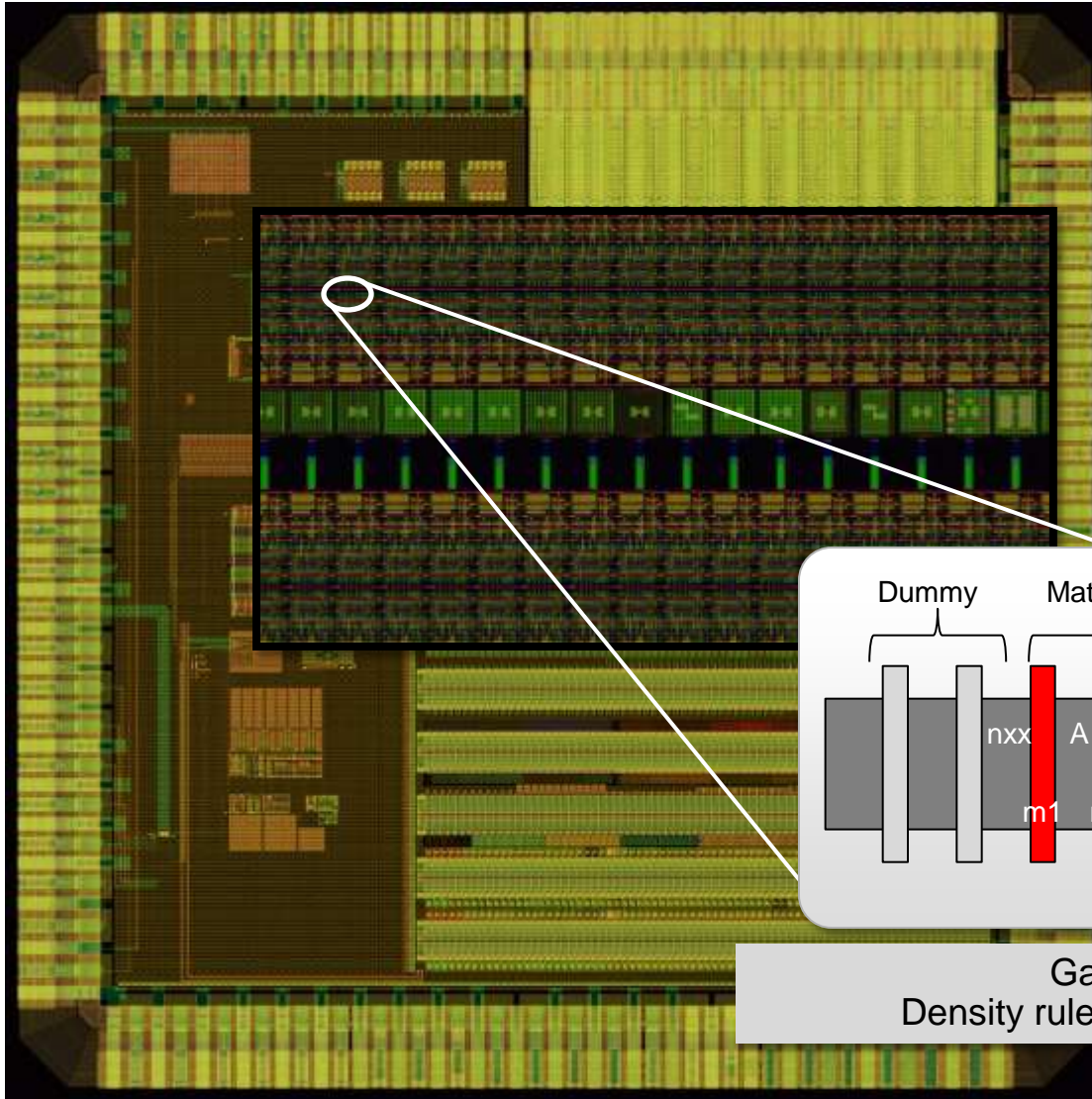
- **DPT (double patterning):** 1500 devices with different layouts and density dependencies providing data for resistor / transistor matching and metal mismatch
- **Analog performance, gate delay:** Ring oscillators and operational amplifiers give early insight
- **Electro-static discharge:** Need to be designed for HBM and CDM performance – for example CDM must be tested across different voltage domains
- **Ability to overstress devices:** Evaluate the reliability degradation due to NBTI, PBTI and HCI



Dense pattern can be split into two sparse patterns

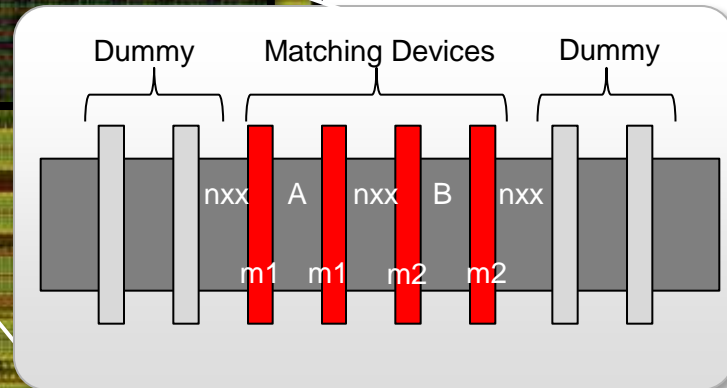


# Test Matrix



## On-Chip

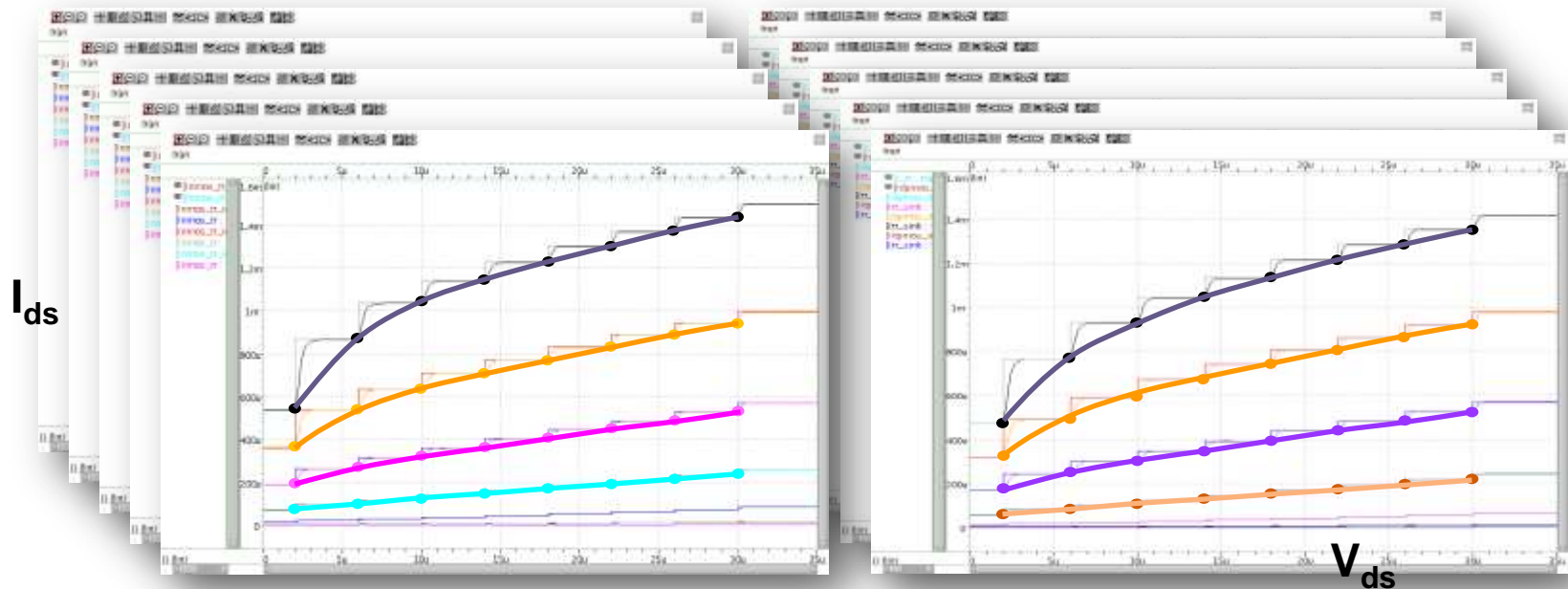
- Device-Under-Test matrix
- I-to-V conversion
- DAC
- Current compare
- Fast BIST testing
- 1,500 test devices
- Matching & density aware



Gate Matching guidelines  
Density rules optimized for analog matching

# MOS characteristic: Classic IV Sweep

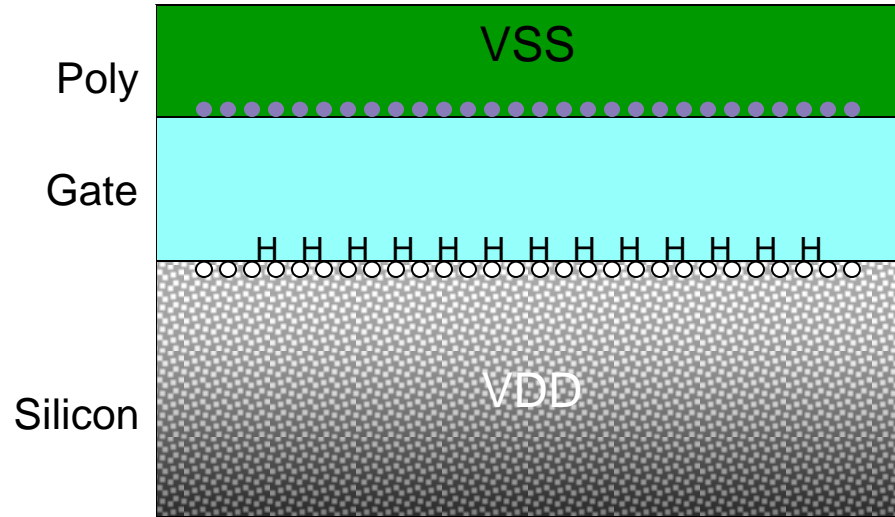
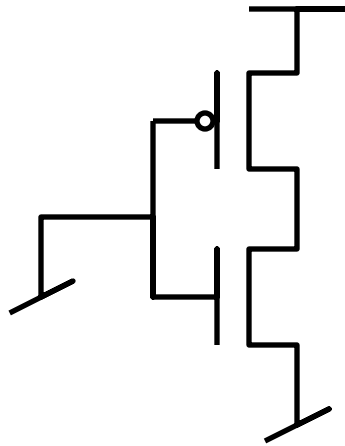
- Test device: NMOS/PMOS: 2.7  $\mu\text{m}$ /0.018  $\mu\text{m}$
- TR simulation:  $V_{gs}$  (0.3V  $\rightarrow$  0.9V) &  $V_{ds}$  (0.1V  $\rightarrow$  0.9V) sweeping
- $I_d$  range: 180 nA  $\rightarrow$  1.50 mA



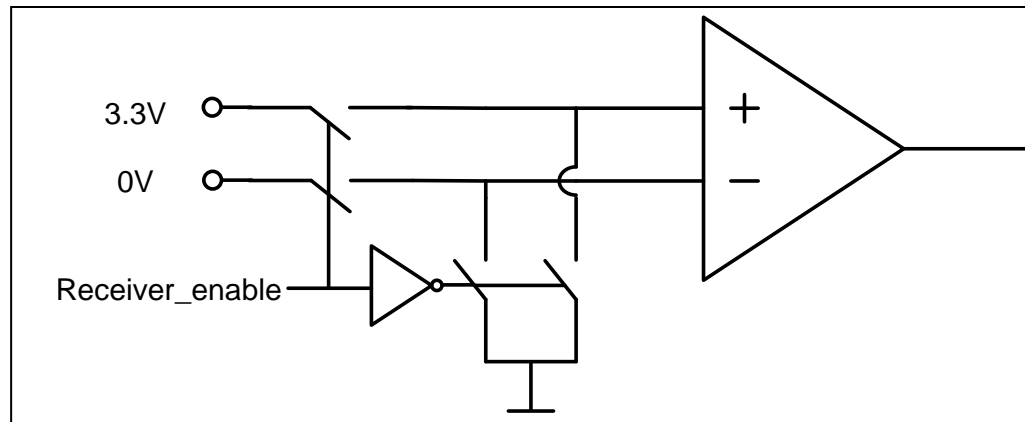
Walk sequentially through all 1,500 devices

# Example of a Simple Circuit Issue

## Simple circuit



## USB Example of NBTI Issue

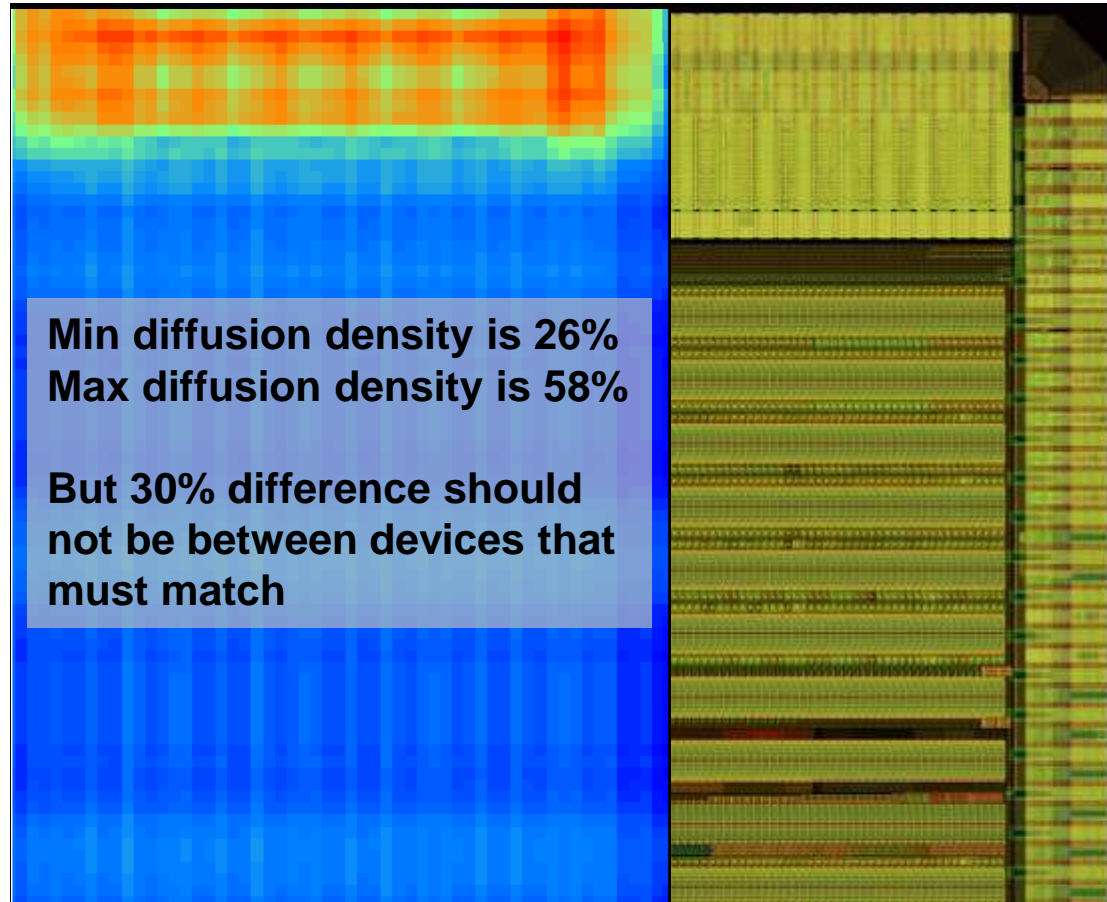


### Mitigation of the NBTI problem:

Introduction of symmetric stress on both inputs to the differential pair by pulling input to the same voltage during suspend mode.

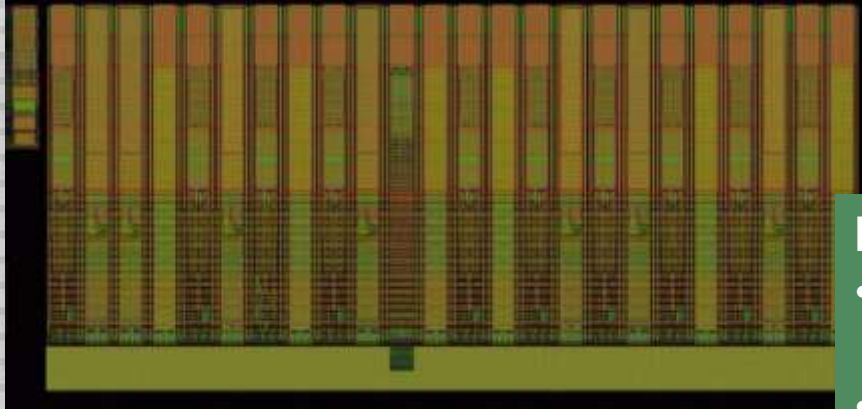
# Layer Densities (Filled)

## *On-Chip ADC example*



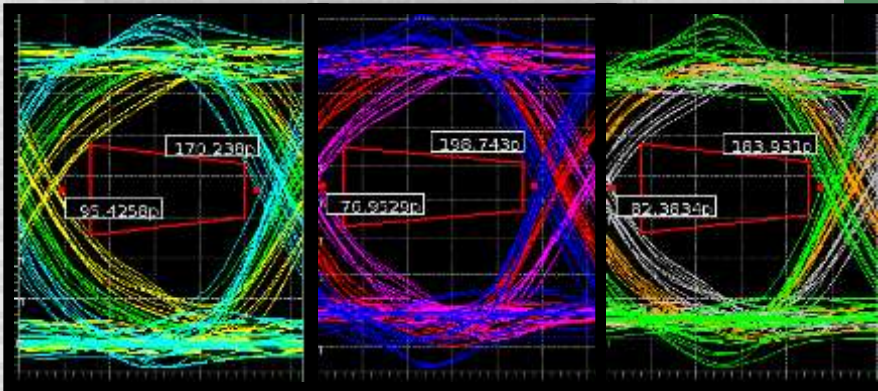
***Know the Issue...  
and Design Around It***

# DDR4 I/O – *Overcoming Design Challenges*



## Implement:

- Novel circuits designed to meet DDR4 as well as legacy DDR3 (wide IO range)
- Pre-emphasis – to help with SI-based losses
- Improved Rx to deal with closed eyes



## Feasibility Results

Showing pre-emphasis performance for  
DDR4 needs above 3.2 Gbps rates

# Key Points

- **Deeper link between layout & performance** in 20-nm required (compared to previous nodes)
- **Double patterning** and its effect on circuit density under different metal stack conditions must be considered
- **Quantization of device sizes and restricted design rules (RDR)** mean no 28-nm re-use, 20-nm is a grounds-up development
- **PPA, schedule and early PDK** necessitates an advanced silicon design methodology with close foundry co-operation

# Agenda

20-nm Design Requirements

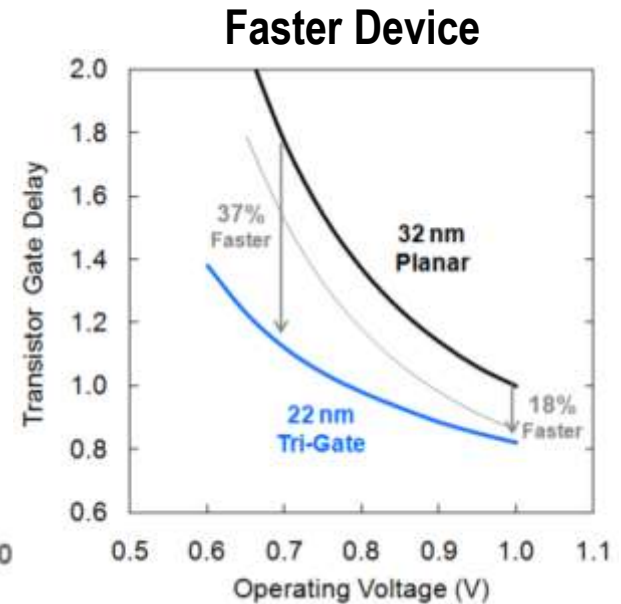
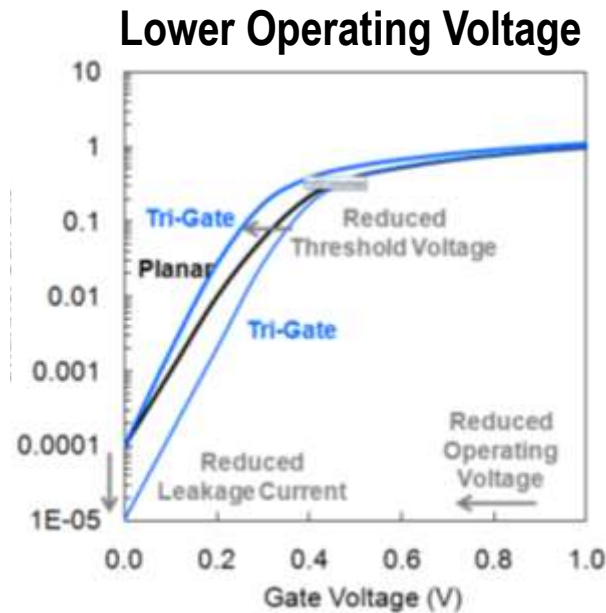
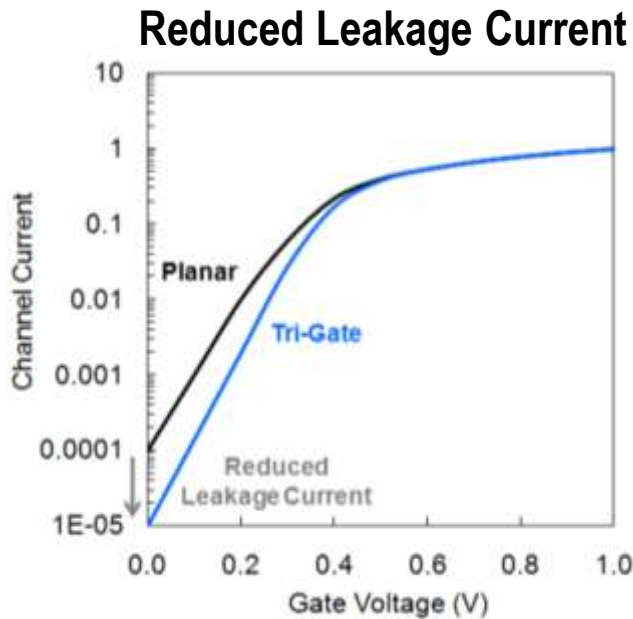
Advanced Design Methodology

**Stepping Stone To FinFET**

Summary



# FinFET Advantage

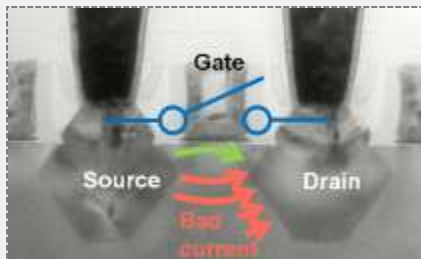
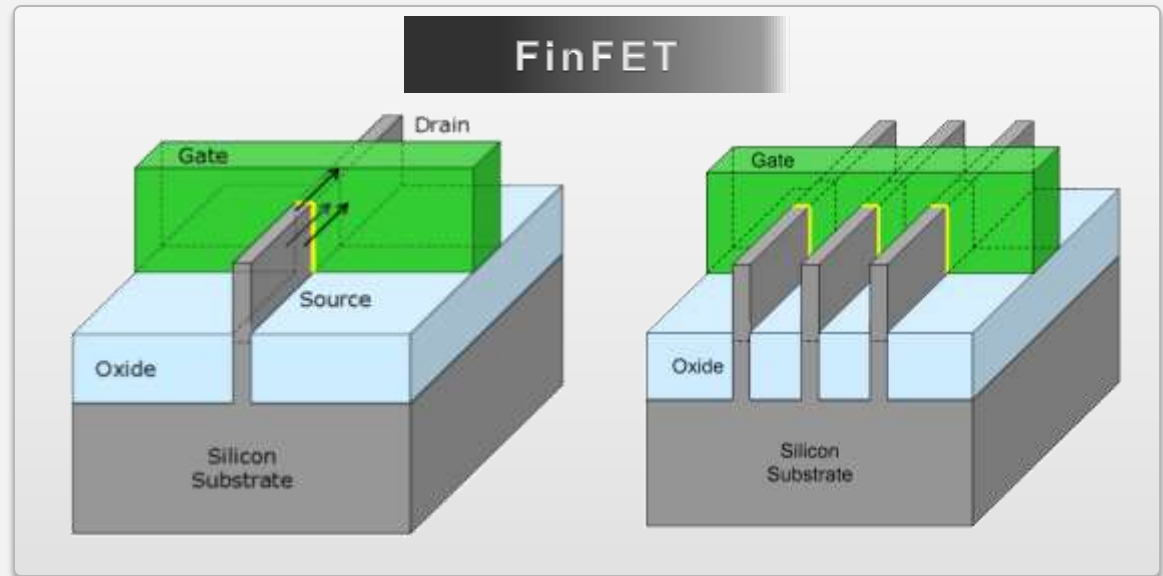
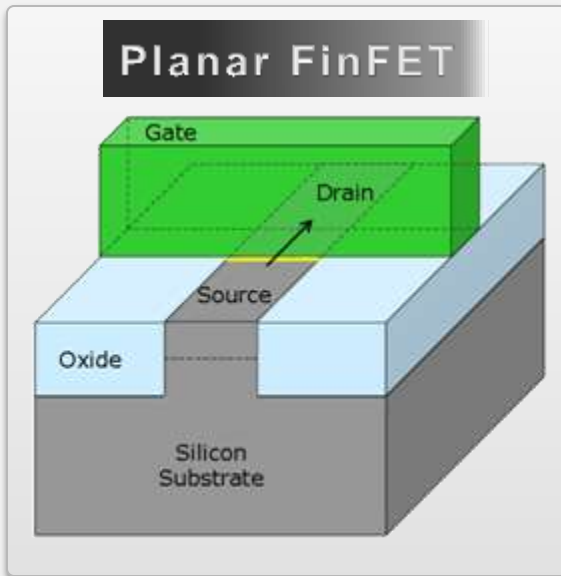


Source: Mark Bohr, Intel Developer Forum 2011

**Example of Intel's FinFET with respect to their 32-nm planar**



# How FinFETs Work



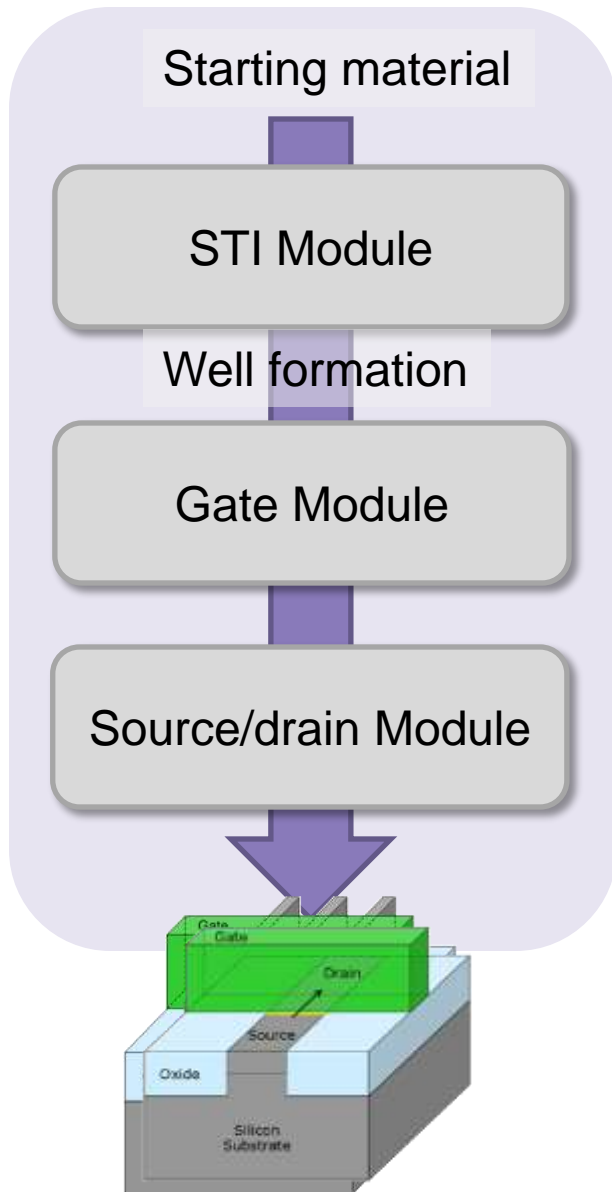
**Single gate** channel control is limited at 20-nm and below

**“Multiple” gate** surrounds a thin channel and can “fully deplete” it of carriers. This results in much better electrical characteristics.

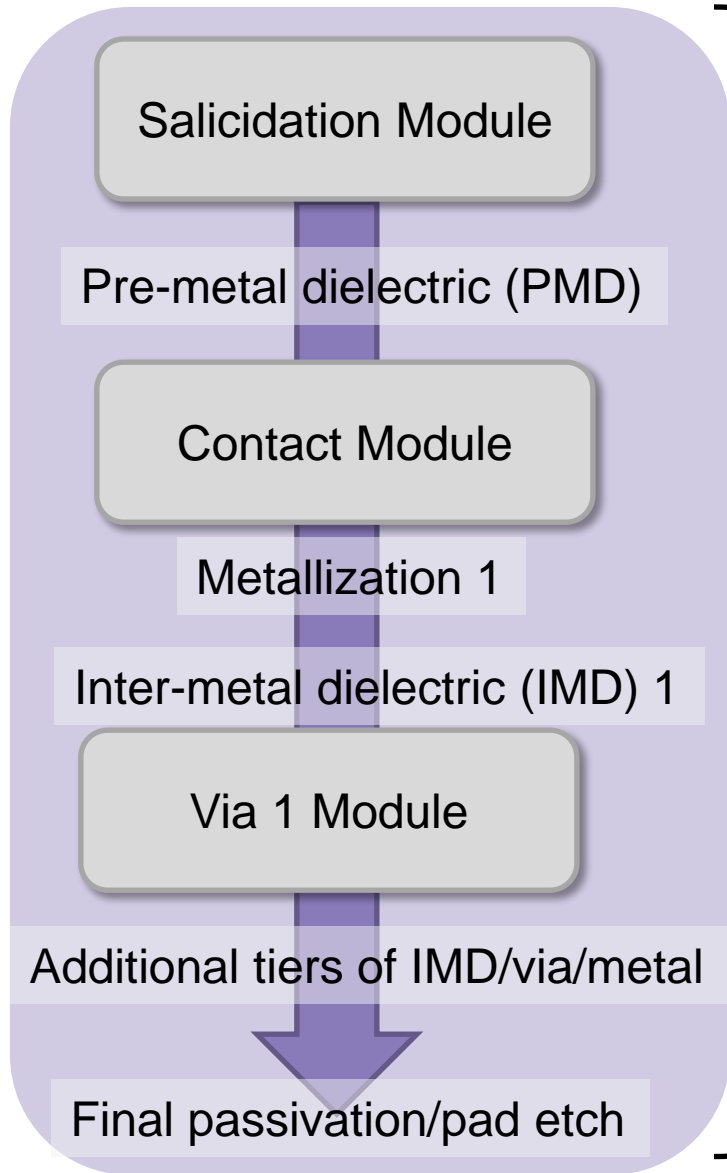
# *Remember this comment?*

*“By being modular, vendors have the option to plug in the FinFET into an existing planar BEOL flow.”*

# FEOL

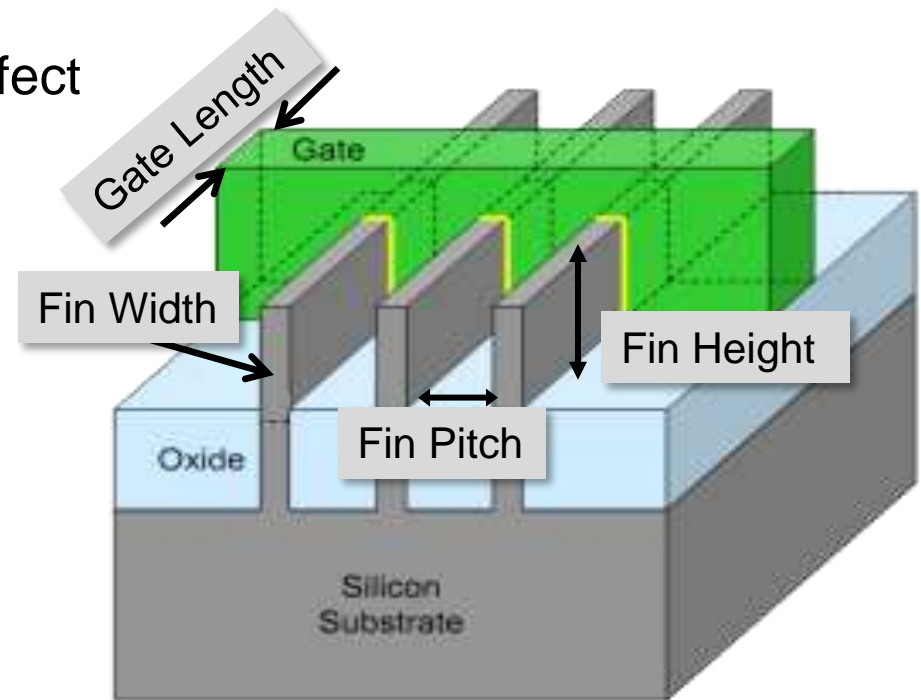


# BEOL



# FinFET Technology Parameters

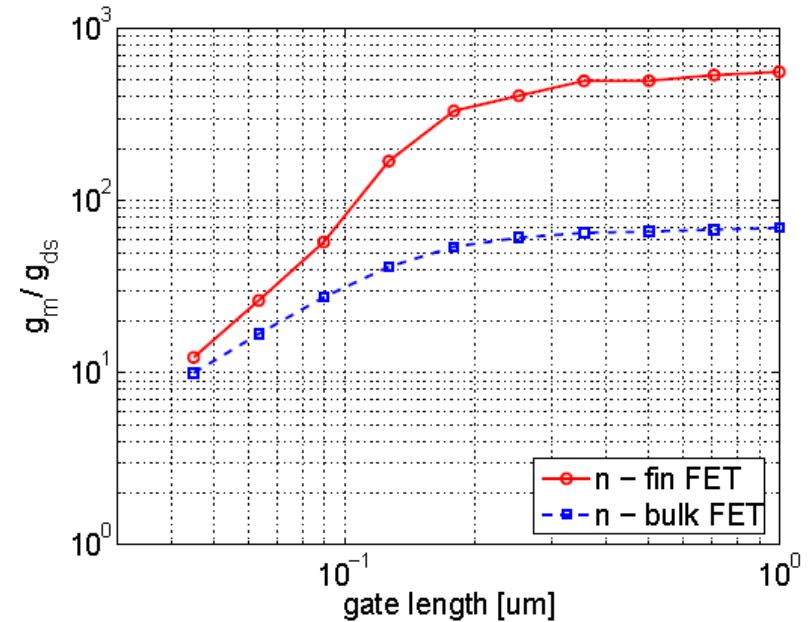
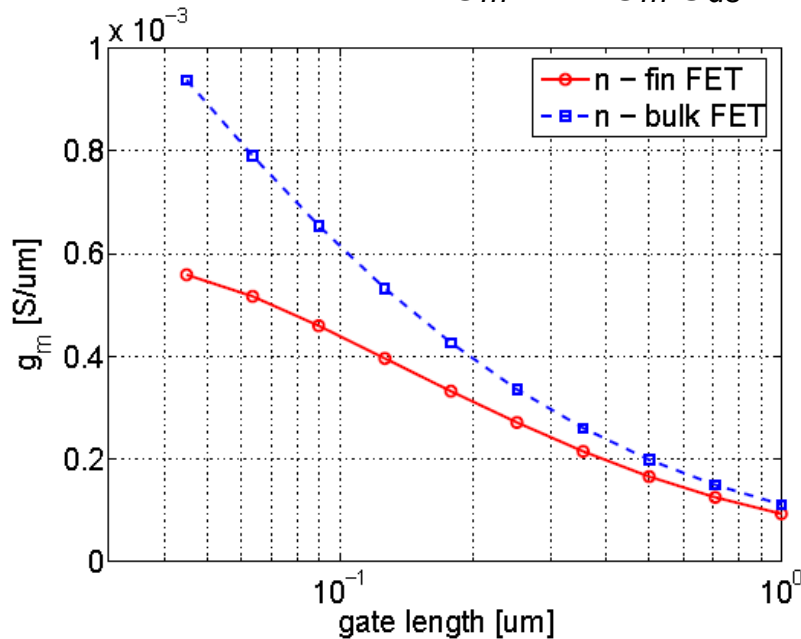
- Fin Width
  - Determines short channel effect (SCE)
- Fin Height
  - Limited by etch technology
  - Tradeoff: layout efficiency vs. design flexibility
- Fin Pitch
  - Determines layout area
  - Limits S/D implant tilt angle
  - Tradeoff: performance vs. layout efficiency



**These parameters are fixed by the process,  
The only parameters a designer can change: #Fin, #gates**

# Planar Versus FinFET Comparison

$g_m$  and  $g_m/g_{ds}$  of bulk and FinFET



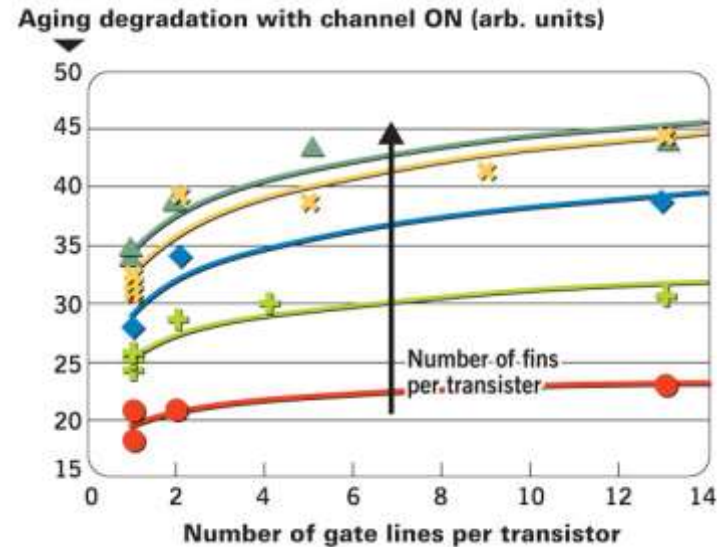
## FinFET's provide:

- Improved sub-threshold and short channel behaviour
- Enhanced intrinsic gain  $g_m/g_{ds}$
- Better matching behaviour
- Metal gates eliminate poly depletion effects
- Lower  $g_m$ , lower  $F_t$
- Lower output conductance

Source: M. Fulde et al.: Analog circuits using FinFETs (2007)

# Matching, Self Heating

$$\sigma_{VT} = \frac{A_{VT}}{\sqrt{WL}}$$

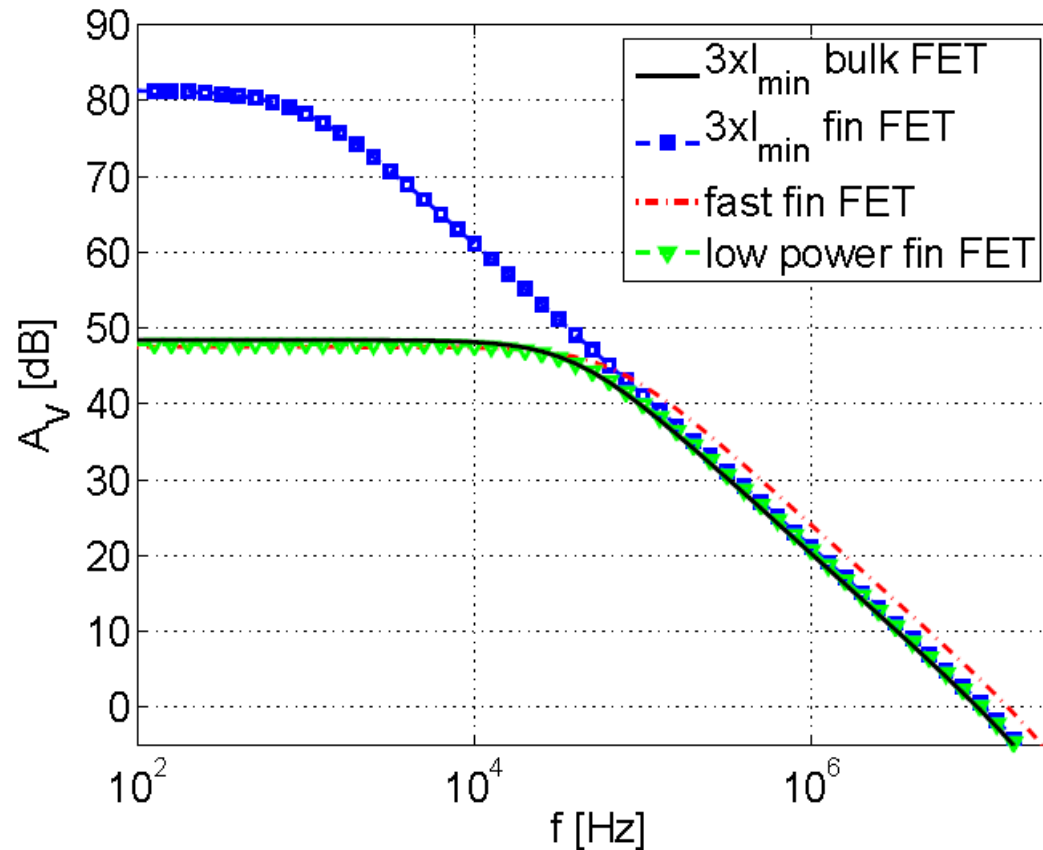


- FinFET's expected to show good matching behaviour
- Area of current sources in DAC's will improve (same matching for a lower area)
- Self-heating shows negligible impact

Source: M. Fulde et al.: Analog circuits using FinFETs (2007), Giuseppe Larosa, IRPS Technical Program 2013 Chair

# Impact Of Higher Intrinsic Gain

Bode plot of planar and FinFET implementations

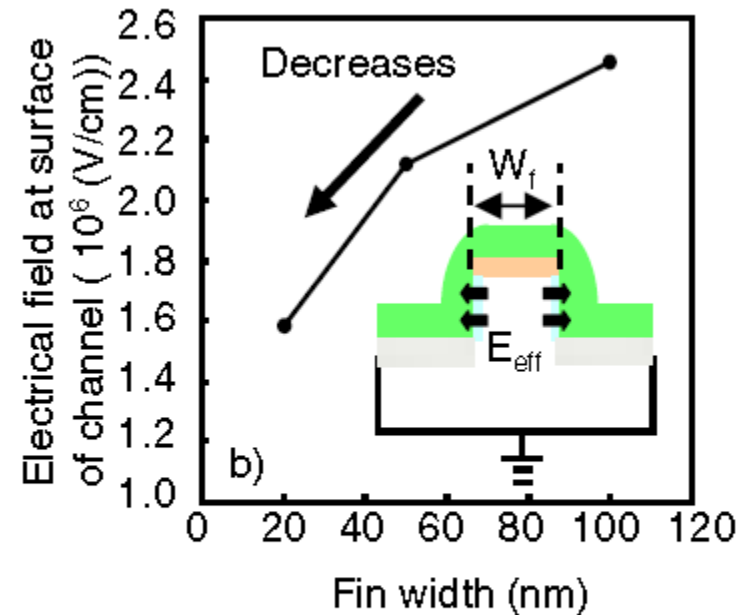
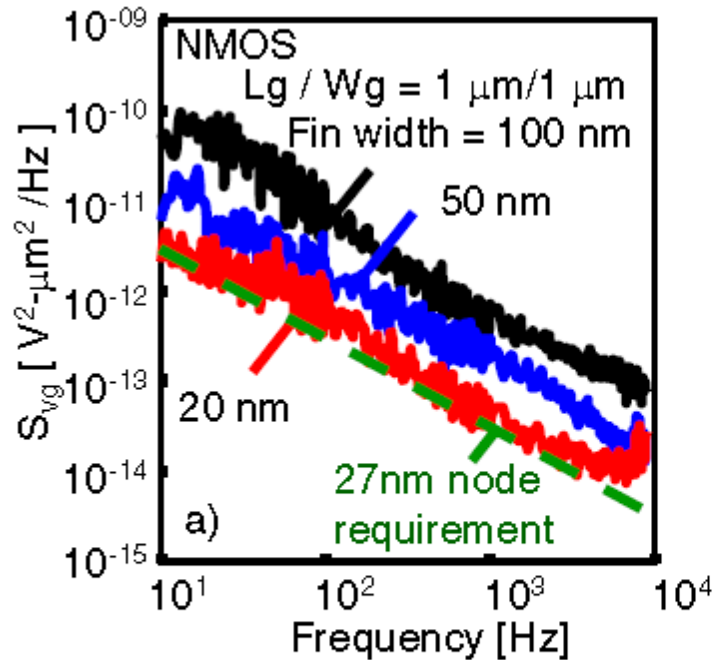


Benefits of the improved intrinsic gain two stage Miller compensated OTA

Source: M. Fulde et al.: Analog circuits using FinFETs (2007)

# Addressing Flicker Noise

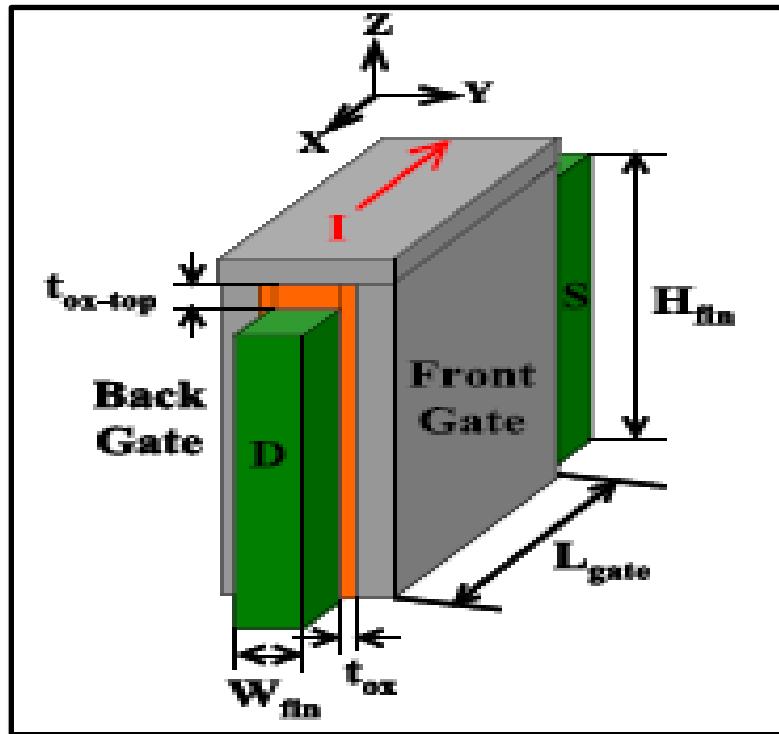
Flicker noise of FinFET decreases with scaling of fin width



Source: "The Optimum device parameters for high RF and analog/MS performance in planar MOSFET and FinFET" Ohguro et. al Y 2012 Symposium on VLSI Technology Digest of Technical Papers



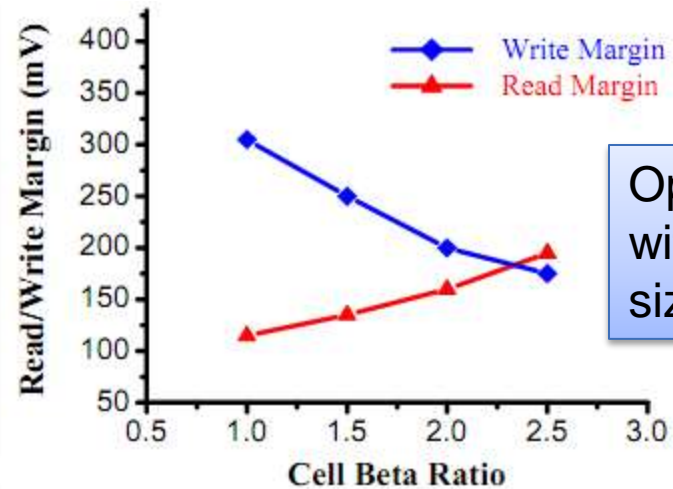
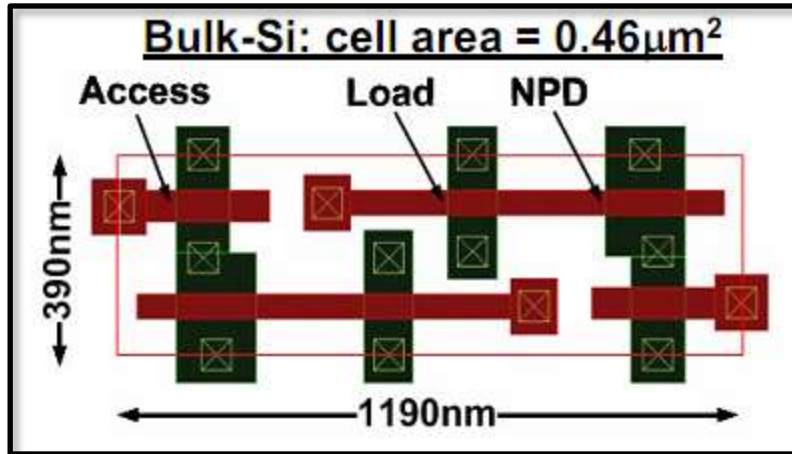
# Higher Gate Capacitance



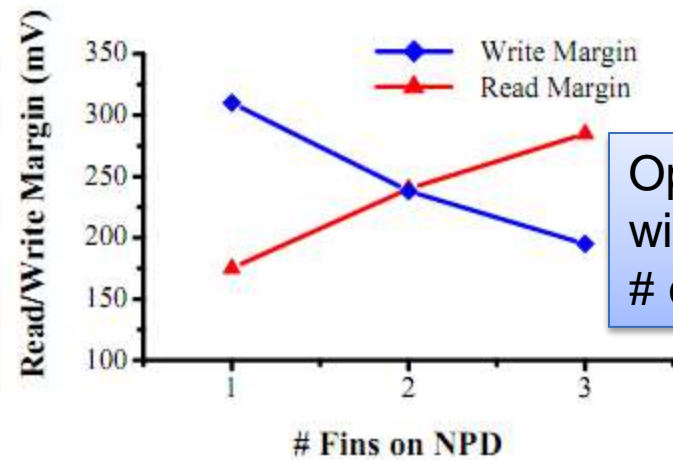
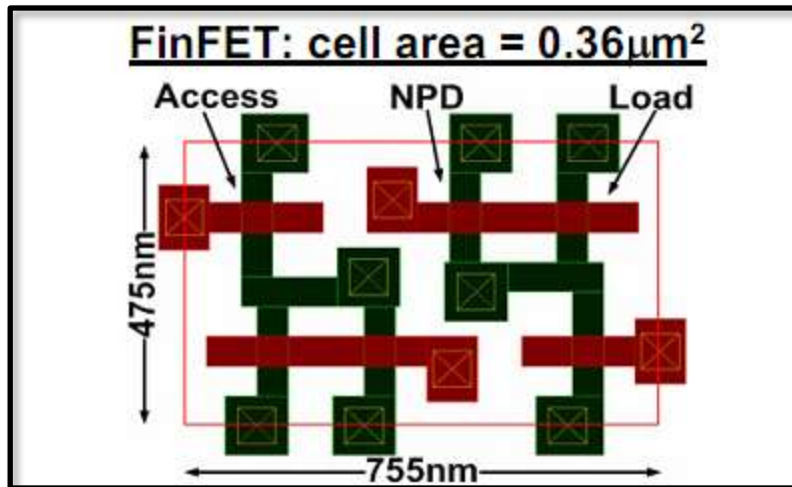
- FinFET has around 2x gate capacitance for the same device size
- Increased power:  
$$I = (2 \cdot C_g + C_{wire}) \cdot V \cdot F$$
- Higher On current
- Optimal device sizing is very critical to harness the power reduction

# Width Quantization Impact on SRAM

## Bulk Si vs. FinFET



Optimization with continuous sizing

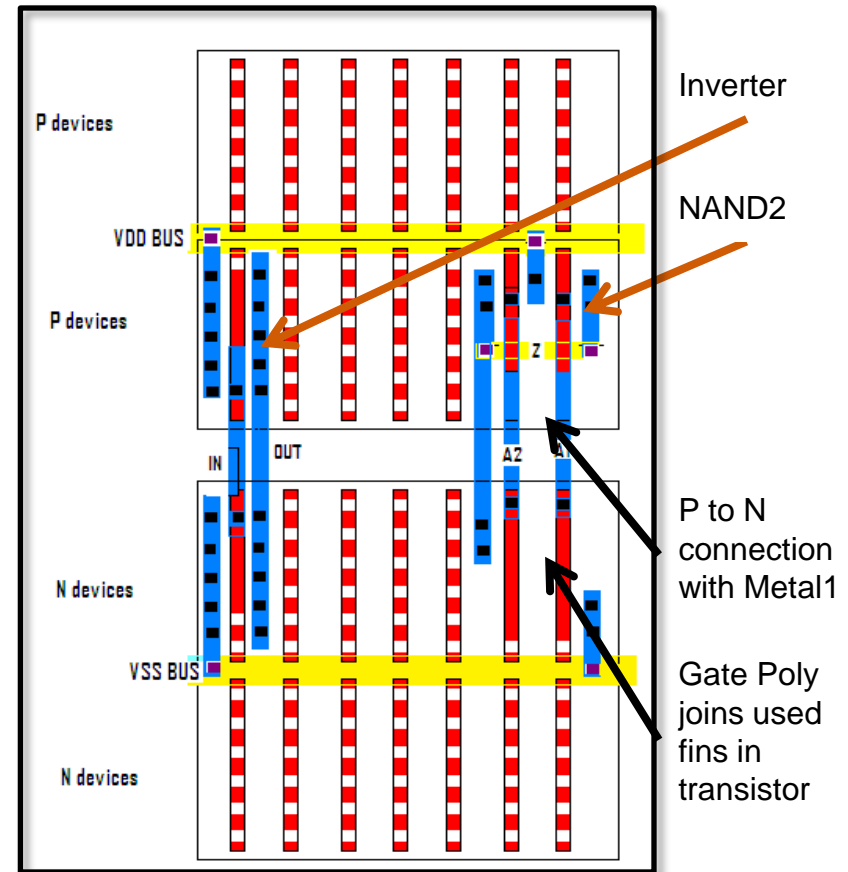


Optimization with discrete # of fins

(Prof. Tsu-Jae King Liu, UC Berkeley)

# FinFET Standard Cells

- **DPT compliant std. cell layout**
  - Early testing through TCAD modeling & simulation
  - Layout faster (built-in features in CD, ICV)
  - Concurrent development process, std. cells
- **Concurrent optimization with P & R**
  - Strict color-compatibility constraints improve placement optimization
  - Optimize cell routability and router enhancements in the context of DPT



*FinFET cell architecture from patent application related to standard cells*

# Design Challenges, Impact, Solutions

Meet PPA, deep sub-micron technology requirements, layout dependent effects, early version of PDK

## 1. Process design rules for manufacturability

- Impact: area, development time
- Solution: earlier SoC floor-planning, new architectures

## 2. System specs have not changed to reflect lower I/O voltages

- Impact: reliability
- Solution: new architectures to handle “high voltage”, aging sims.

## 3. Different core devices with lower $g_m$ & $g_d$ , higher gate leakage

- Impact: analog design
- Solution: new architectures

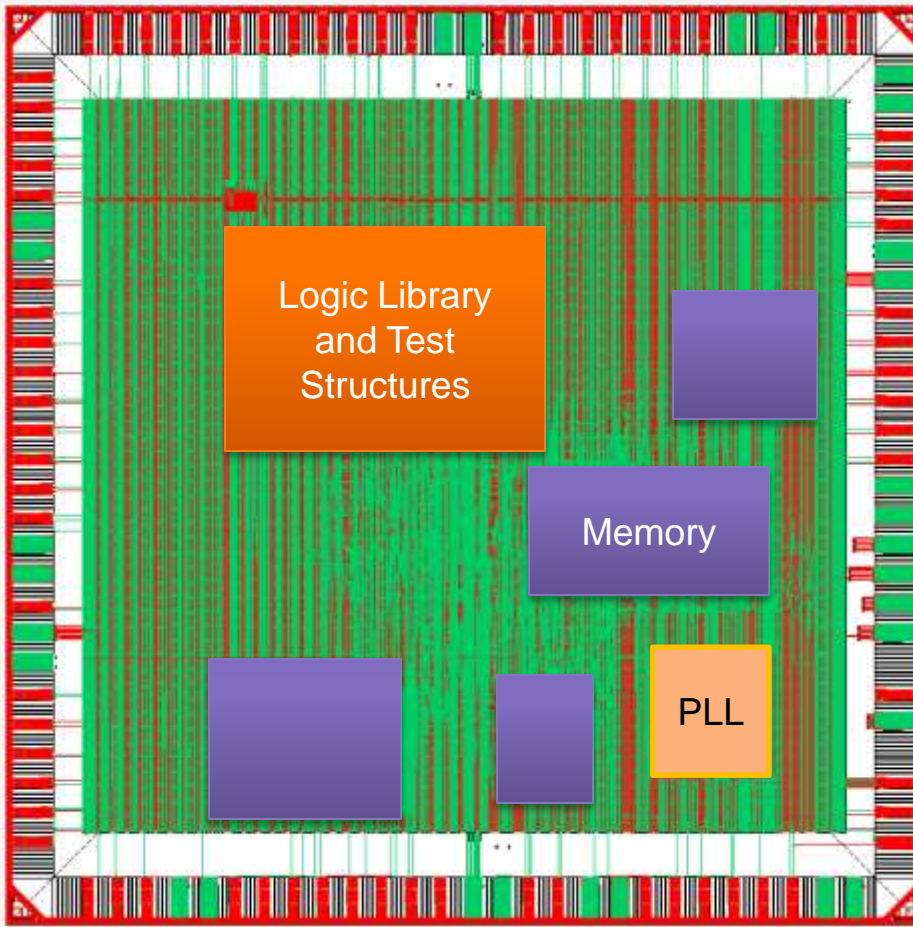
## 4. Meet scaling trend, SoC integrators expect analog/mixed-signal IP to scale

- Impact and solution: new architectures needed

*Remember what I said about  
advanced silicon design methodology?*

# Advanced Silicon Design Methodology

## FinFET



- Early memory IP qualification vehicle
- Characterization structures:
  - PLL
  - SRAMs
  - Test Structures
  - Logic library
- Enables process correlation to simulation models

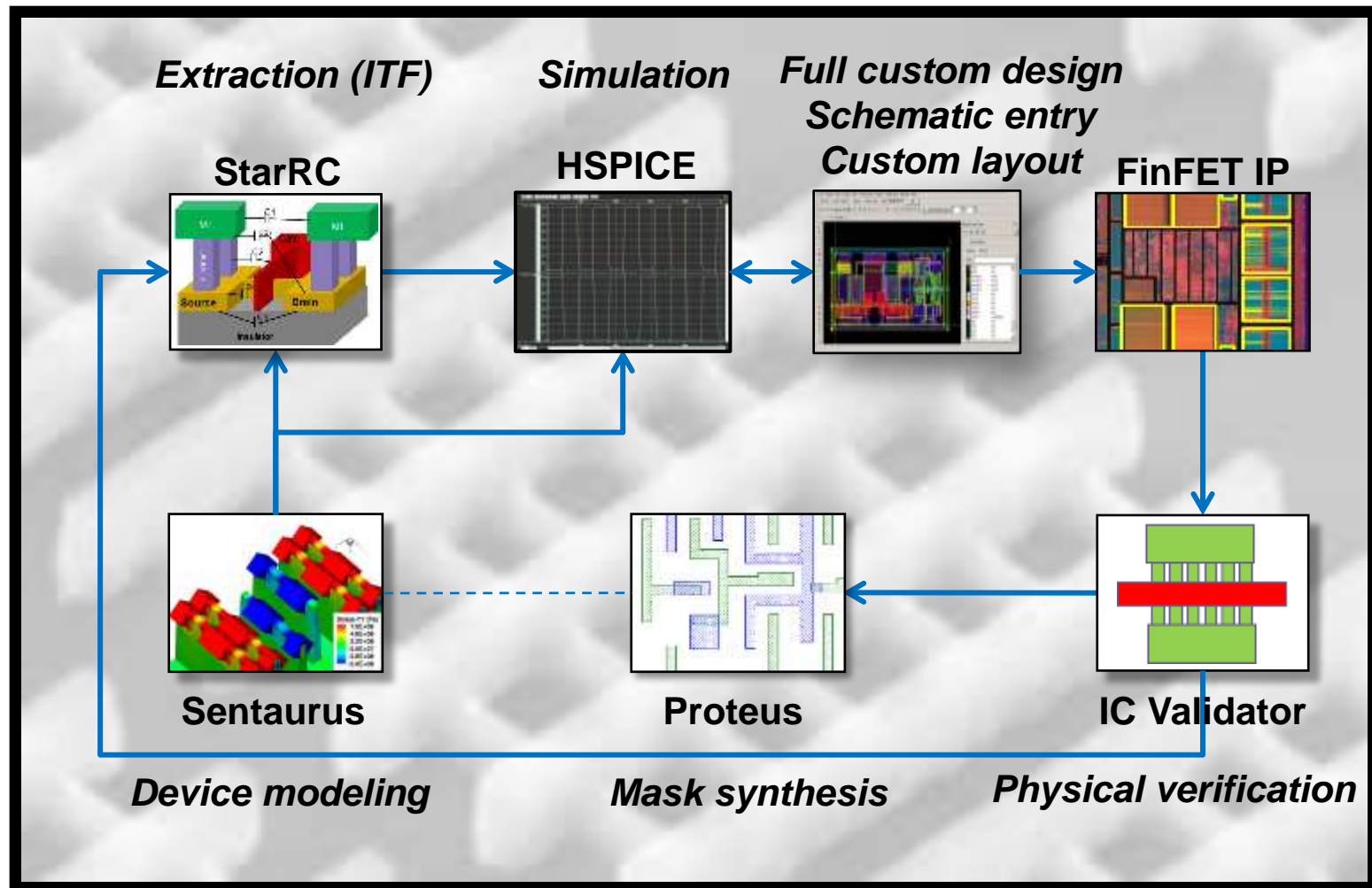
# Technology Assessment Chip

## *Key Points*

- **Very early PDK** used for technology assessment chip
- **PDK variations** methodology had to adapt to known and unknown changes
- **Highly experienced engineers required** (analog, mixed-signal, layout, process, CAD) that could handle the uncertainty
- **CAD flow verification (fill, DRC)** significantly helped in meeting the next set of 14-nm FinFET analog/mixed IP tape-outs

***But...for FiNFET's you need more...  
an infrastructure (tools, extraction, device simulation)***

# It Takes A Village...





# Sentaurus TCAD

- **Sentaurus Process**

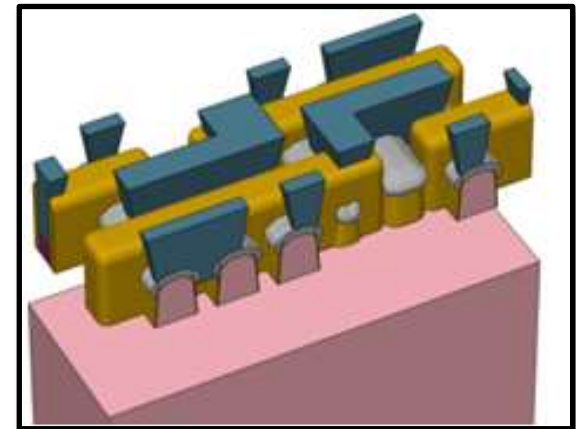
- Plasma model enables optimization of Fin doping

- **Sentaurus Device**

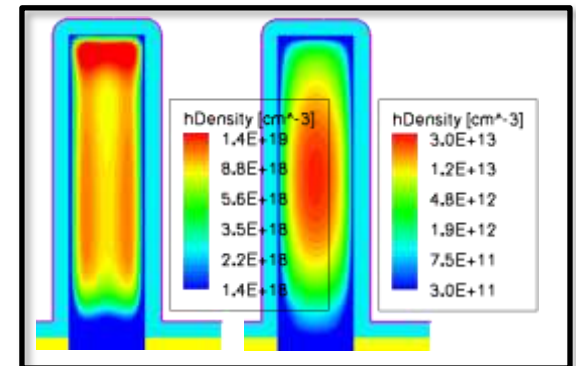
- Simulate the current along sidewalls and top of the fins, for on-state and off-state
- Analyse random process variation < 14-nm
- Characterization of proximity effects

- **Used at foundries and IDMs**

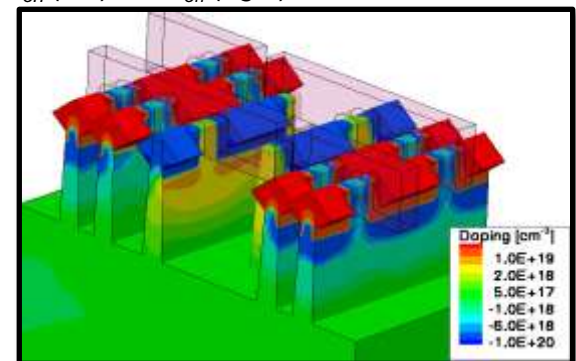
- Effect of Fin geometry on scaling, electrostatics
- Optimization of processing flow, doping, stress



*FinFET SRAM cell showing 3D structure*



*$I_{on}$  (left) and  $I_{off}$  (right) in Fin cross section*



*Doping proximity effects in SRAM cell*

# FinFET Impact On The Designer

*“Being modular, vendors have the option to plug in the FinFET into an existing planar BEOL flow.”*



Same metal → no impact to the mixed-signal designer

The impact of FinFETs is largest below metal 1: standard cells, memory compilers and full custom design such as analog/mixed-signal, are impacted.

Double patterning and restricted design rules, while associated with FinFETs, are not unique to them; they are necessary for planar technologies → this 20-nm planar experience can be applied to standard cells, memory compilers and full custom design



# Evolution Of Electronic Devices

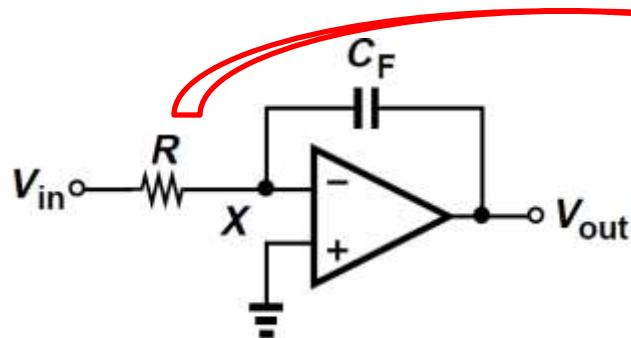
- Triode vacuum tube
- BJT transistor
- MOSFET transistor



# Circuit Invention Triggered By New Devices

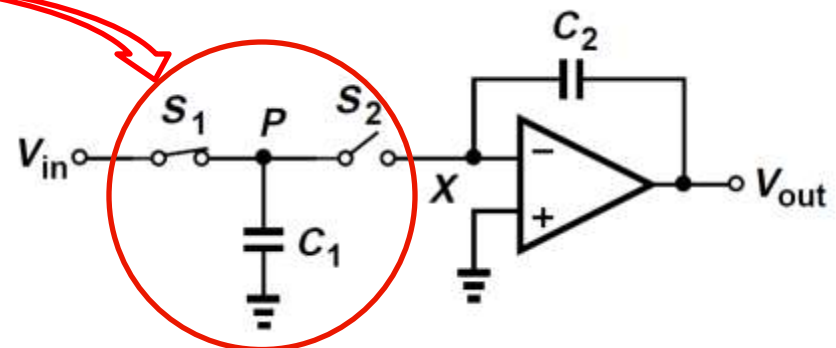
## The continuous time integrator

- Pole freq. is a function of  $R$  and  $C_F$ 
  - Precision of  $R$  is very limited
- Pole freq. is inversely proportional to  $R$ 
  - Impractical to have large  $R$ 's in IC
  - $R$  requires trimming for precision



## The switched capacitor integrator

- Pole freq. is a function of ratio of  $C$ 's
  - High accuracy and stability
- Pole freq. is proportional to  $C_1$ 
  - Small  $C$ 's are easy to implement
- Only practical in CMOS
  - BJT not good switches, off leakage



- SC architectures enabled by MOSFET devices
- Used in most integrated analog functions: Filters, Data Converters For Communication, Audio, Signal Processing

# Analog/Mixed-Signal Design *In The FinFET Generation*

New architectures will be created to solve the design challenges and take advantage of the characteristics of FinFET:

- Lower leakage
- Higher intrinsic gain
- Higher speed
- Abundance of devices

The micro-electronics innovation cycle  
New devices → Challenges → Innovation

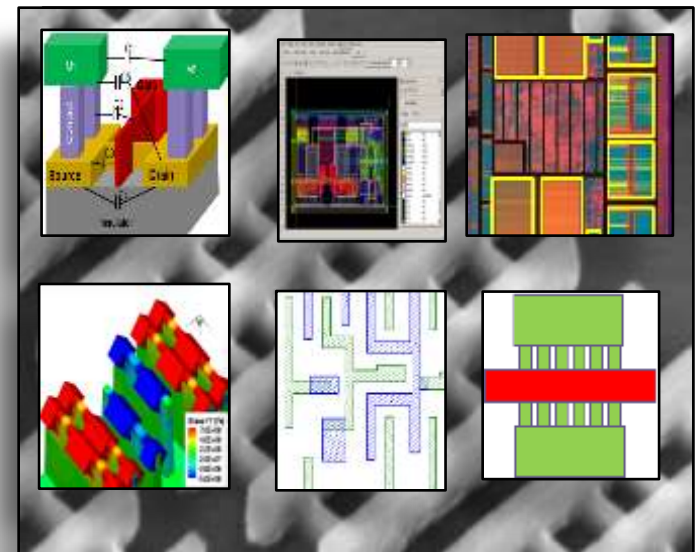
# Agenda

20-nm Design Requirements

Advanced Design Methodology

Stepping Stone To FinFET

**Summary**



# 20-nm (Planar) Mixed-Signal IP A Stepping Stone To FinFET?



*Is this true?*



*Is this the right question?*



# Summary

- **Designers care about the same parameters** ( $g_m$ ,  $g_d$ ,  $F_t$ ,  $F_{max}$ , matching, noise) in planar or FinFET to get performance while meeting the SoC constraint of power, area
- **20-nm planar provides designer with DPT and RDR experience**,  
→ stepping stone to FinFET
- **Additional stepping stones are related to methodology**
  - **Process qualification vehicles** using early design kits necessary to provide insight into impact on CAD verification and analog performance
  - **New architectural development** planar (28-nm → 20-nm) required new architectures to meet power, performance and area, same applies to FinFET
- **Change to FEOL impacts transistors** changing analog performance, the same BEOL (metal) has no impact
- **Designers will leverage FinFET properties** to invent new circuits